

# **Overview of S3IP Expertise Area in Microsystems**

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# S3IP Mission and Capabilities

*A New York State Center of Excellence*

## Mission:

connect companies with university capabilities to generate economic impact, with focus on electronics manufacturing.

## Technical capabilities:

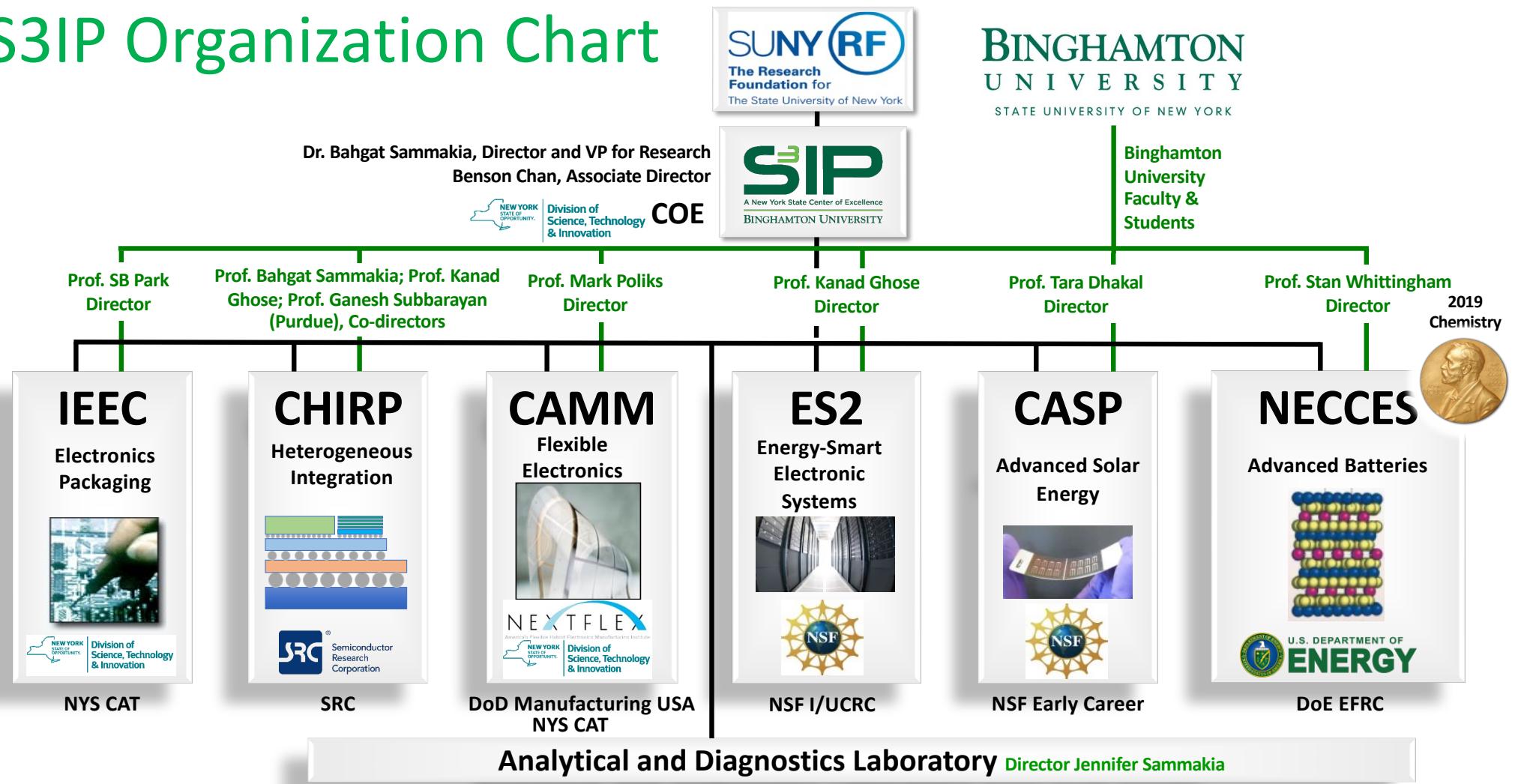
- Thermal management
- Failure analysis & reliability for electronics packaging
- Manufacturing processes and materials
- Energy storage & harvesting



Division of  
Science, Technology  
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# S3IP Organization Chart



# **Electronics Packaging and Related Activities**

- Diagnostics, Failure Analysis (ADL, IEEC)
  - 150+ years of collective expertise of ex-IBM experts
  - Cross-sectioning and other imaging
  - Reliability assessments
- Metrology and materials characterization of interconnections, interposers, solders, TIMs, printables (IEEC, CAMM, CHIRP, ADL)
- Flexible Electronics (CAMM)
  - Printable electronics
  - Flexible substrates
  - Applications
- Measurements in general at Advanced Diagnostics Lab (ADL)
- Modelling at all scales (IEEC, ES2, CHIRP)
  - Mechanical (stresses, warpage, evaluation of mechanicals for packaging) (IEEC, ES2)
  - Fluid dynamics in general (IEEC, CHIRP, ES2)
  - Evaluation of thermal and mechanical properties (IEEC, ADL)
  - Digital twins for microelectronics manufacturing and packaging (ES2)
- Advanced package cooling solutions (ES2, CHIRP):
  - Development of liquid cooling solutions and multi-scale evaluation using thermal test vehicles (TTVs)

## Other Microelectronics-Related Activities

- Active participants and Chapter Leads:
  - IEEE EPS Heterogeneous Integration Roadmap
  - SRC's Microelectronics and Advanced Packaging Roadmap
  - iNEMI roadmap
- Co-founding member, executive board member and proposal co-authors for SRC's Manufacturing USA Institute:



- Co-lead of SUNY-wide STRIVE initiative on Microelectronics and Advanced Packaging
- Co-organizer and alternate host for IEEE Packaging Conference
- Responded to several other CHIPS Act call with other partners



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**Dr. Stephen Cain, Senior Research Support Specialist  
ADL and IEEC Capabilities**

**April 28, 2025**



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# ADL Industry Partners: last 12 months

**Unison**

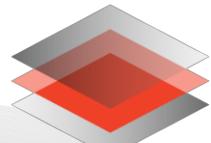
**BAE SYSTEMS**



A Delta Group Company

**Amphenol**  
Aerospace

**TTM Technologies**



**NHanced  
SEMICONDUCTORS**



AMES GOLDSMITH™

**GlobalFoundries™**



# ADL Staff



**Jenny Sammakia**  
*ADL Director & Research Assistant Professor*  
PhD, chemistry  
University of Wales, Bangor



**Yan Sun**  
*Manager (HSCF) & Research Scientist*  
PhD, chemistry  
Michigan State University



**Anju Sharma**  
*Senior Scientist*  
PhD, physics  
Delhi University, Delhi



**Dae Young Jung**  
*Chief Senior Scientist*  
PhD, physical metallurgy  
University of Illinois Urbana-Champaign



**Matt Wahila**  
*Chief Technology Officer & Research Scientist*  
PhD, physics  
Binghamton University



**Lan Yao**  
*Research Scientist*  
PhD, biophysics  
University of Rhode Island



**Ola Habboub**  
*Research Scientist*  
MS, materials engineering  
Binghamton University



**William Butler**  
*Research Engineer*  
MS, mechanical engineering  
Binghamton University

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**Zhilu Liang**  
*Research Scientist*  
PhD candidate, mechanical engineering



**William Blazey**  
*Technical Analyst*



**Steve Cain**  
*IEEC Lab Manager and interim Associate Director*  
PhD, Cornell

# ADL Expansion: Materials Science Core Facility (MSCF)

8000 ft<sup>2</sup>, established 2007

50 pieces of major instrumentation  
(upgraded/new 2021)

## Sample Prep Suite

## Optical Microscopy Suite

## Thermal Mechanical Suite

## Electron Microscopy Suite

- **FIB-SEM**
- **TEM**
- Multiple FE-SEMs

## X-ray Suite

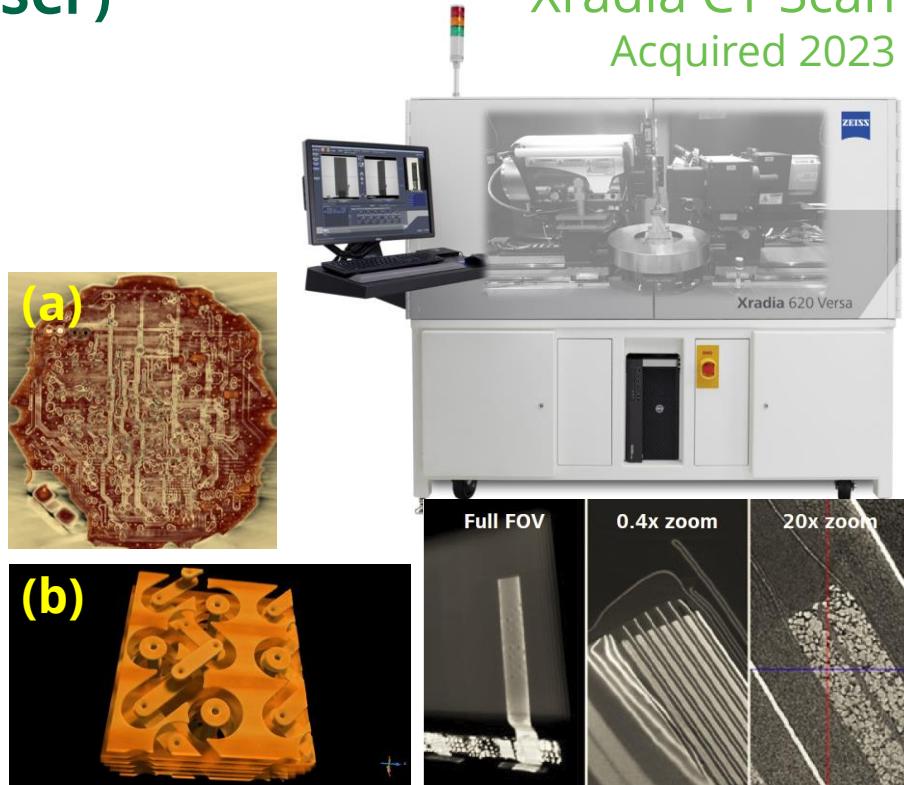
- XRD w/ Hot Stage
- **X-ray tomography**



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## Equipment Spotlight: Xradia CT Scan Acquired 2023



(a) Smartwatch PCB XRM image and (b) XRM 3D video

Smart watch battery: XRM scans the intact battery to identify areas of interest and zooms-in for high resolution imaging

# Zeiss X-Radia Versa 620 3D X-ray Microscope

- Non-destructive 3D X-ray CT imaging with 500 nm resolution for a broad range of sample shapes, sizes, materials, and sample working distances.

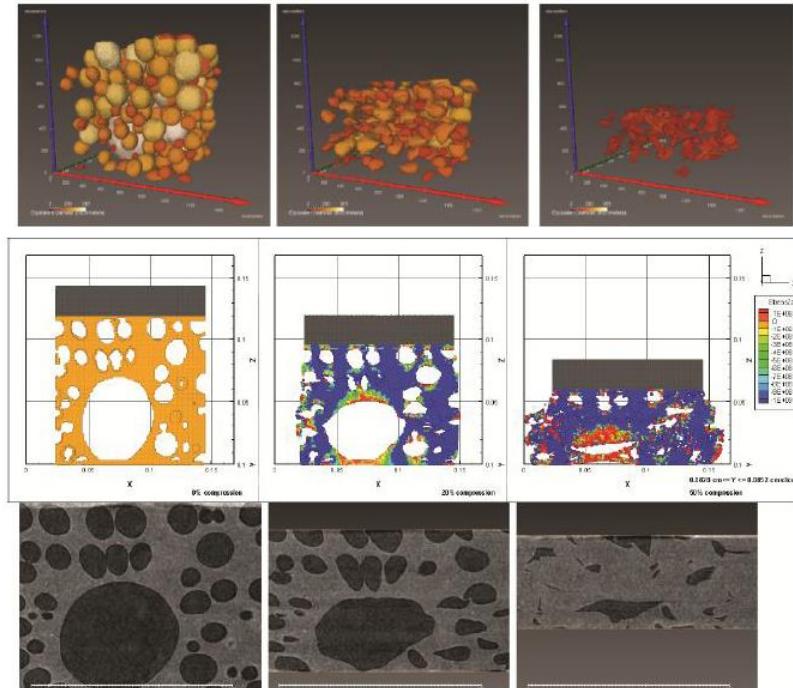
<b>Max FOV</b>	<b>5 cm diameter x 5 cm height</b>
<b>Max FOV (with FPX detector)</b>	<b>14 cm diameter x 9.3 cm height</b>
<b>Max FOV (with auto stitching)</b>	<b>14 cm diameter x 16.5 cm height</b>
<b>Max Sample weight</b>	<b>25 Kg</b>
<b>Sample stage travel</b>	<b>5 cm, 10 cm, 5 cm (x,y,z)</b>

- 160 kV, 25W X-ray source with set of (0.4X, 4X, 20X, 40X) objective lenses for 3D high-resolution images.
- Flat panel detector for fast imaging and large FOV.
- Tension/compression and thermal stage for in-situ imaging of microstructures in controlled environments.

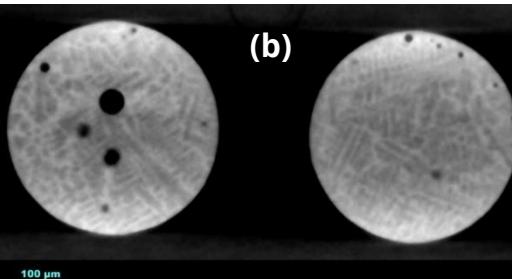
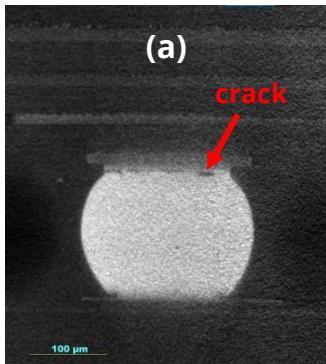
## Applications:

- Electronics Packaging, Life Sciences, Li-ion batteries, Additive Manufacturing, Materials Research and more....

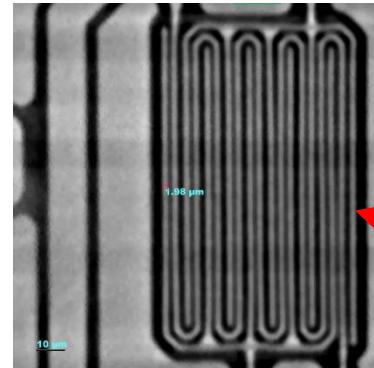
Polymer foam compression studies using X-Radia's in situ capabilities.



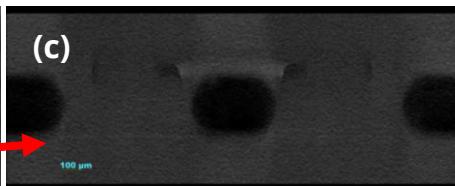
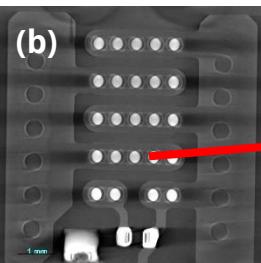
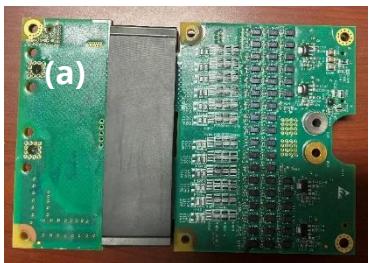
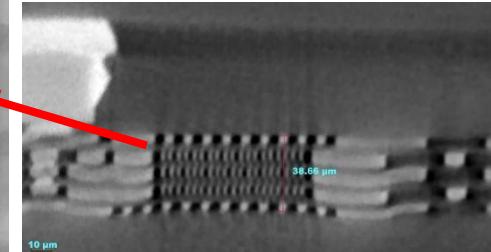
# X-Radia – Examples of 3D X-ray Microscopy



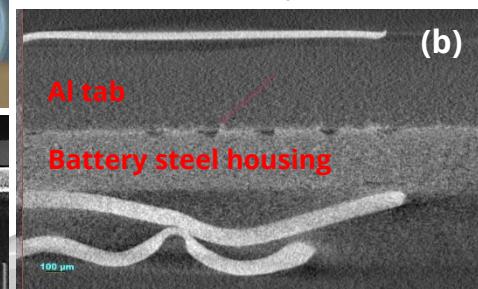
Virtual cross section of a 2.5D package reveals (a) C4 bump solder cracks and (b) internal microstructure.



X-ray CT cross-sections of RDL layers and circuitry in a 3D package.



(a) Large board with flip chip FET devices, (b) CT slice of FET device at 11 µm resolution, and (c) scan at 2 µm resolution show solder ball cracks.



X-ray CT cross-sections of (a) bad and (b) good laser welds of busbar to battery cell.

# FEI Dual Beam Focused Ion Beam Microscope

## Parameters

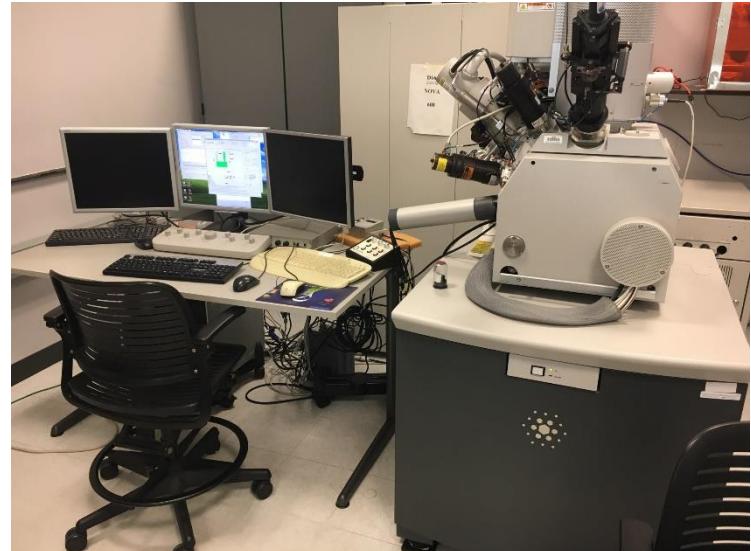
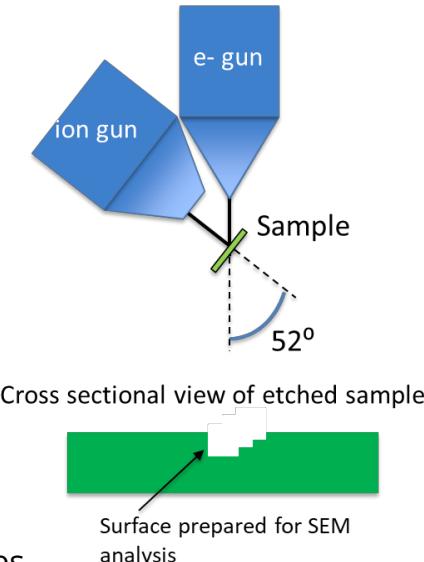
- 1-30 KV e-gun and i-gun (Ga ion)
- Secondary electron and through lens detectors
- Magnification 80X to >200 KX

## Modes of operation

- E-beam imaging / EDS analysis
- Fine feature etching
- Pt deposition

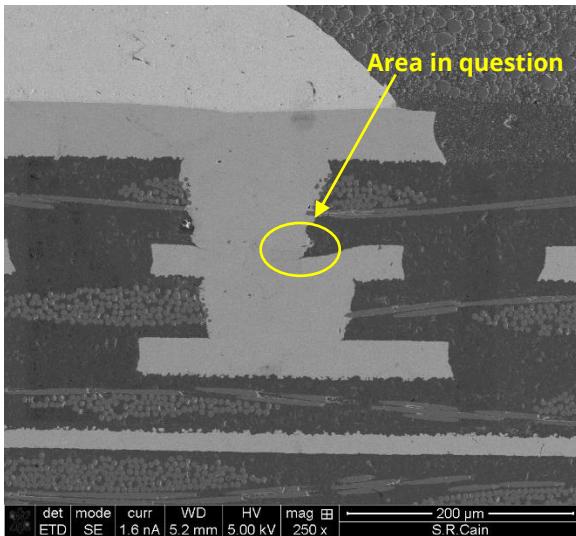
## Applications

- Simple device fabrication via etching and deposition
- Failure analysis of electronic devices
- Sample preparation for transmission electron microscope

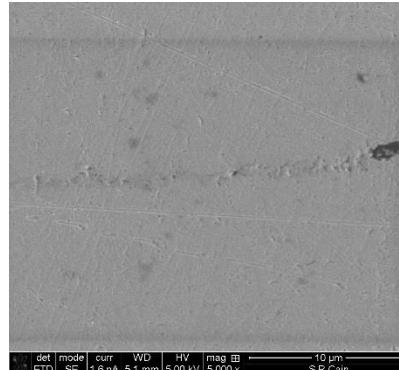


# FIB - Typical Processing Sequence

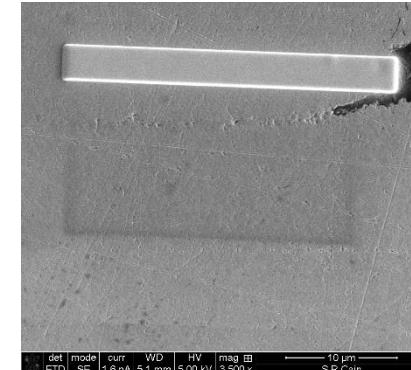
Low mag image of the failed via



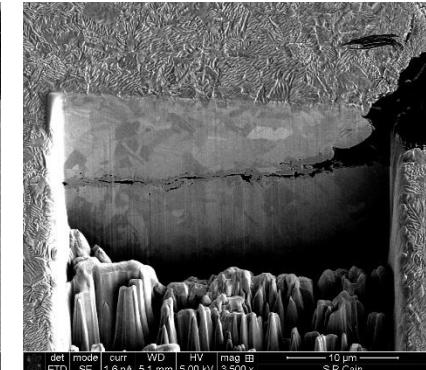
E-beam image of the area



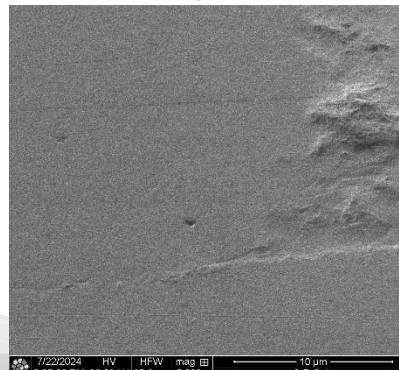
E-beam image of the Pt bar



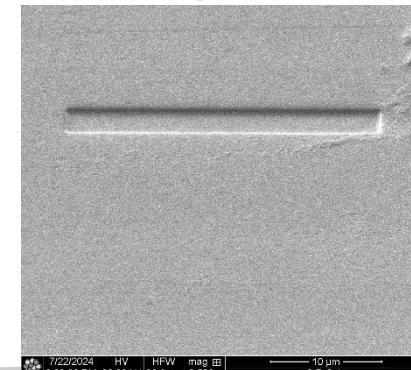
E-beam image of the FIB cut



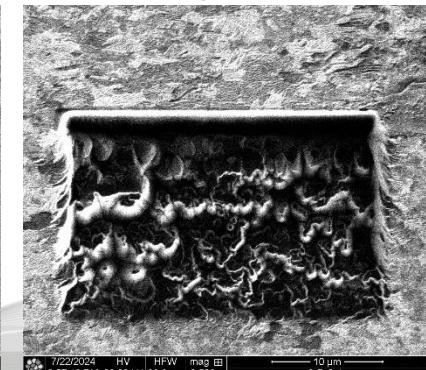
I-beam image of the area



I-beam image of the Pt bar



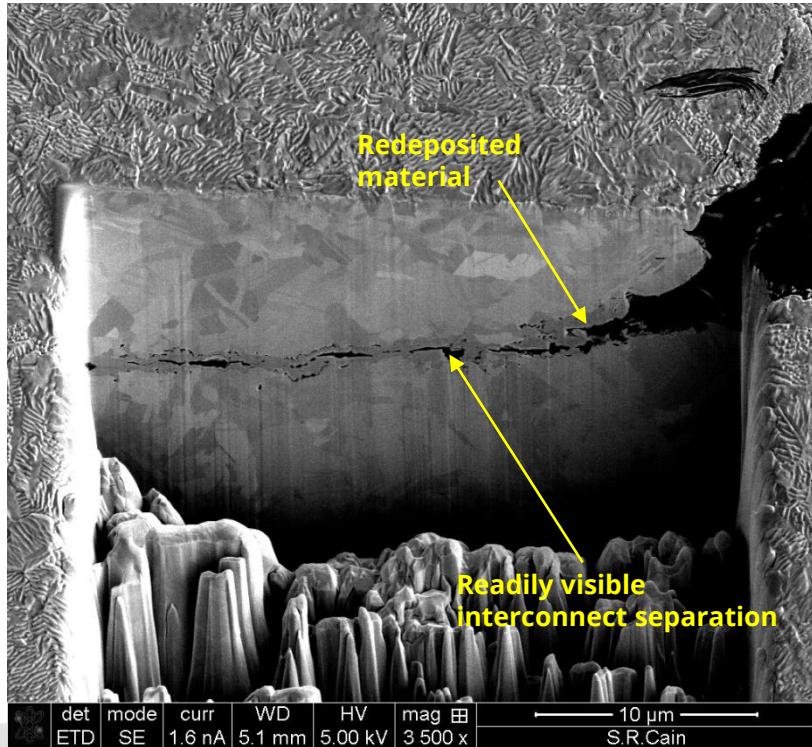
I-beam image of the FIB cut



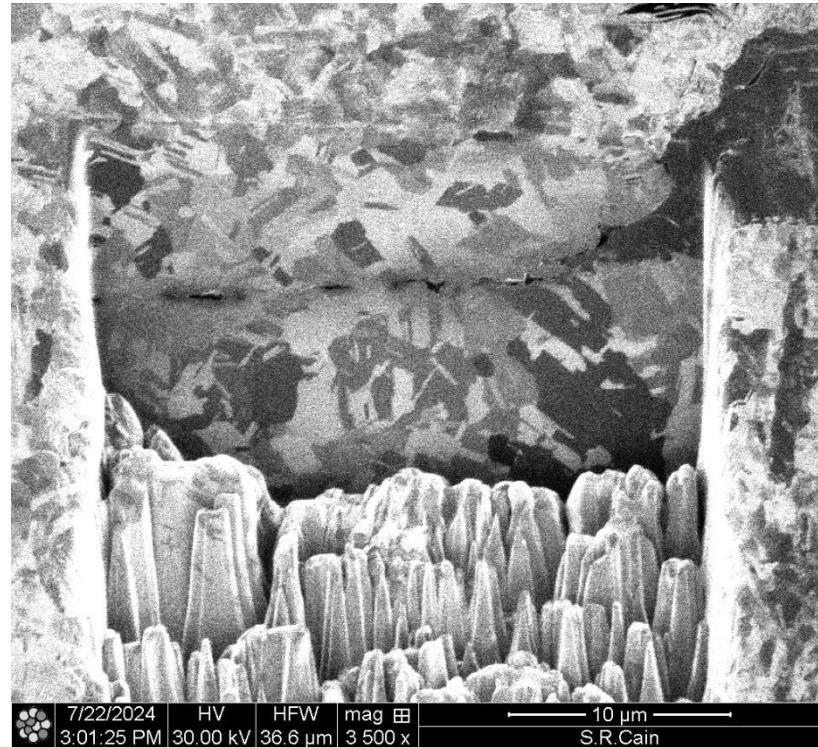
**FIB cut made at a glancing angle, with etching being done across the interface**

# FIB - Final Cut of the Sample (3500X Mag.)

Electron image



Ion image (after 180° stage rotation)



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Cu grain structure is readily seen in both images; very pronounced in the ion image

# JEOL 2100F Transmission Electron Microscope

## Parameters

- Acceleration: 200 KV
- Minimum spot size: 0.2 nm
- Magnification: up to 1.5 MX

## Modes of operation

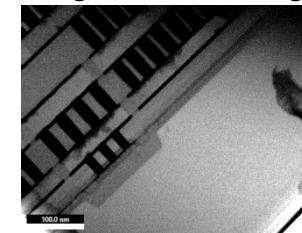
- TEM with Gatan camera
- STEM with bright field detector
- Selected area diffraction
- EDS and EDS mapping (in STEM)

## Applications

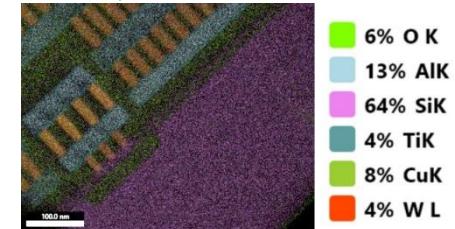
- Electronics / samples prepared via FIB
- Biological / samples prepared by dehydration and staining protocols
- Biological and thin film / samples prepared with microtome
- Nanoparticles / quantum dots, particulate dispersions, nanorods



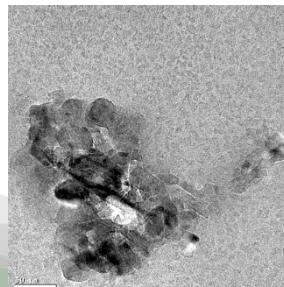
Integrated circuit image



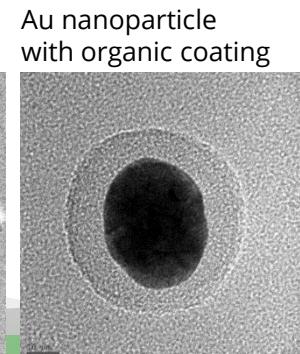
EDS map



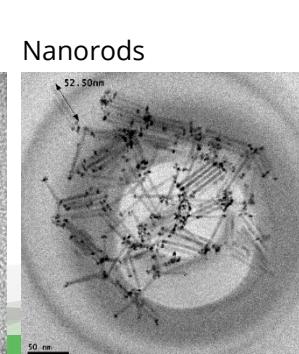
$\text{Al}_2\text{O}_3$  nanoparticle cluster



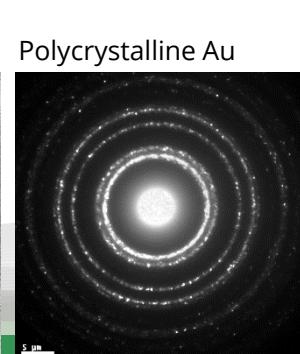
Au nanoparticle with organic coating



Nanorods

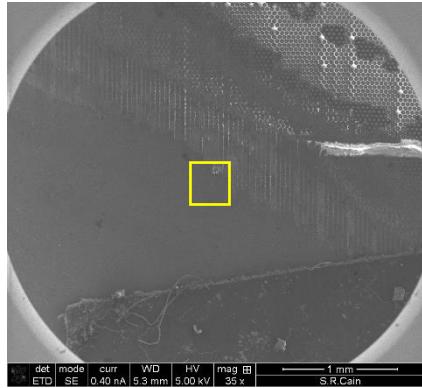


Polycrystalline Au

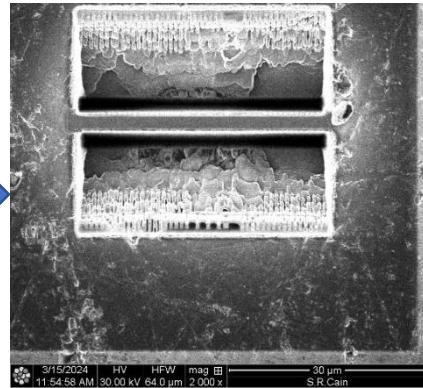


# TEM - Analysis of Integrated Circuit with FIB Prep

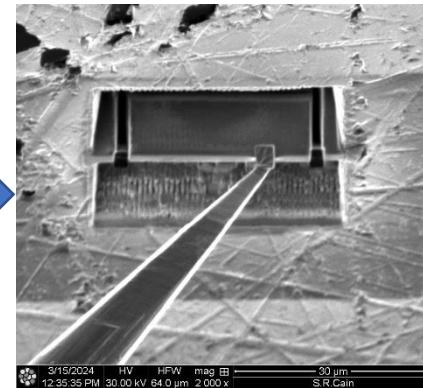
Region of interest



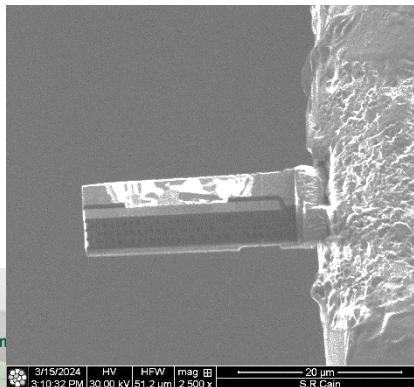
Dual FIB trenches



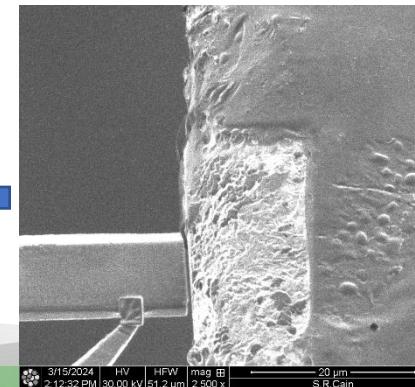
Probe connection



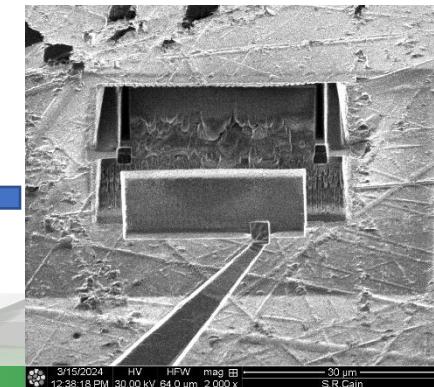
Thinned and polished



Slice mounted to TEM post



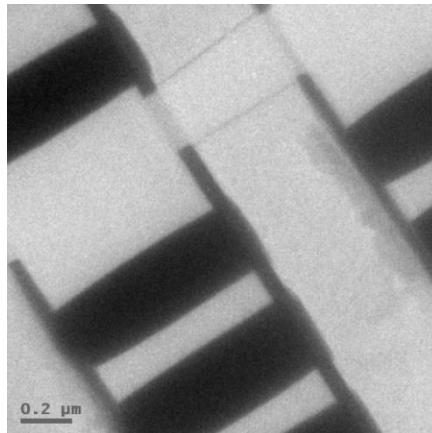
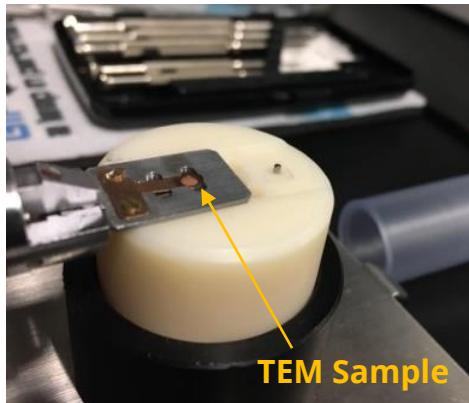
Slice removed



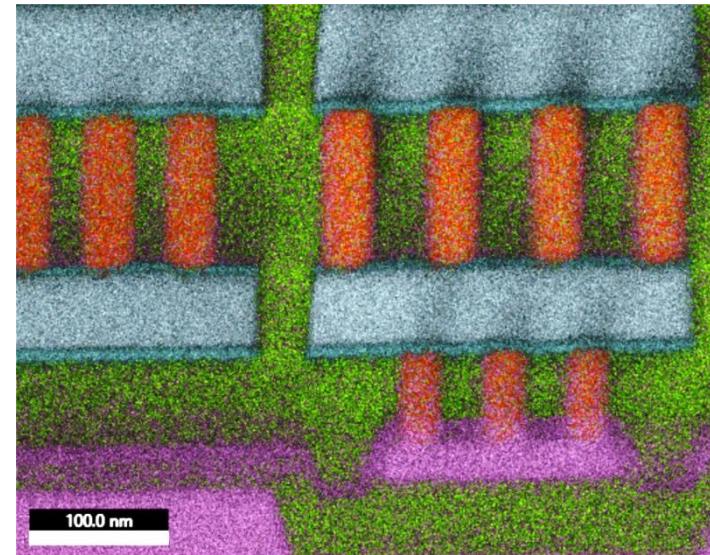
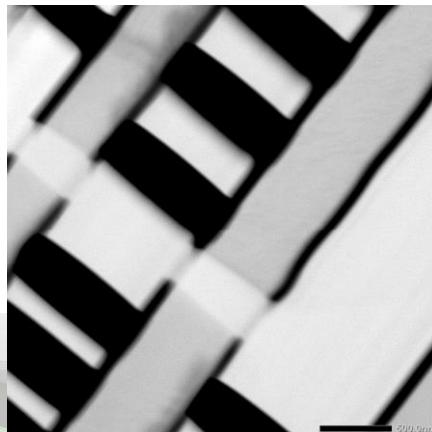
Target thickness  
is 200-300 nm

# TEM - Imaging & EDS Analysis of Integrated Circuit

TEM Image at 50 KX

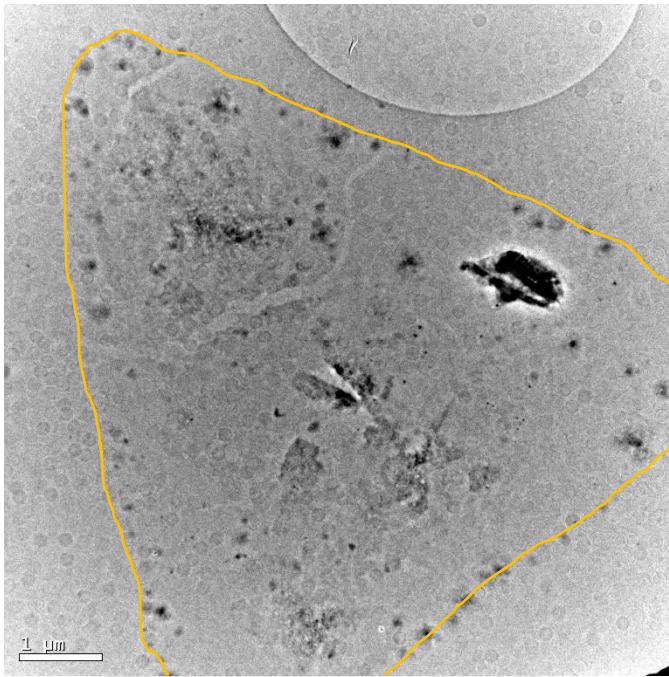


STEM Image at 50 KX  
(run in scanning mode)



# TEM - Electron Diffraction of Ultra-thin MoS<sub>2</sub>

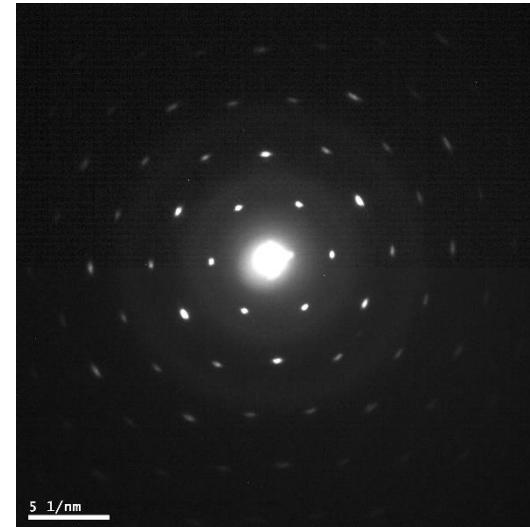
TEM image at 10 KX (outline of MoS<sub>2</sub> flake is sketched because it is nearly impossible to see)



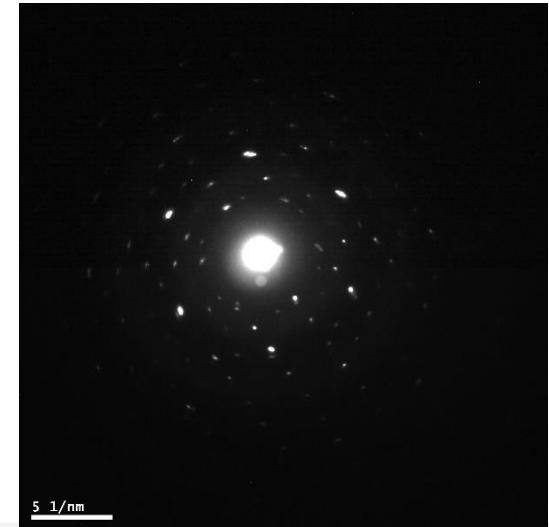
## Graduate student research project

- Ruiqi Zhang
- Consulting staff member, S.R. Cain

Single phase



Mixed phase

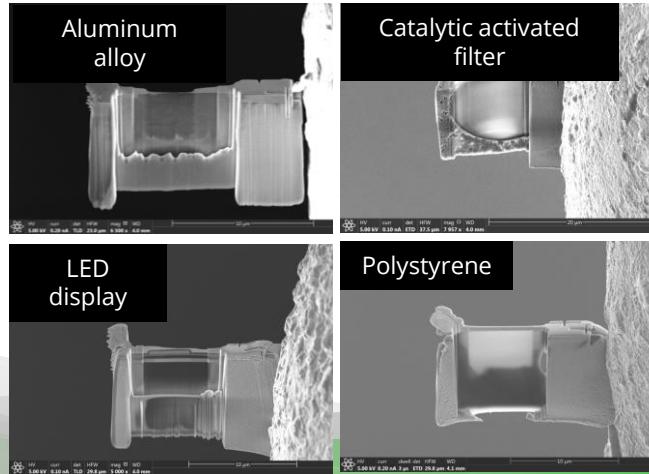


# Thermo Fisher Helios 5 PFIB-SEM (coming Q1 2025)

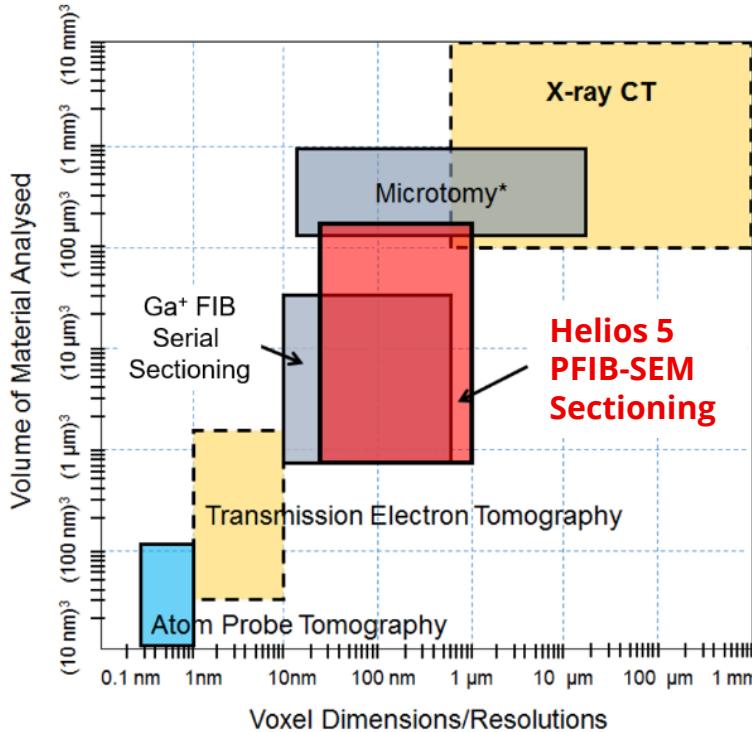
## Base System

- ✓ Extreme high-resolution Field-Emission SEM
- ✓ Plasma-FIB etching with up to 4 ions (Xe, Ar, O, N)
- ✓ Easy-Lift™ nanomanipulator for TEM sample prep
- ✓ EDS for 2D and 3D compositional mapping

Multiple ion species  
enables efficient  
milling of a wide  
variety of materials.

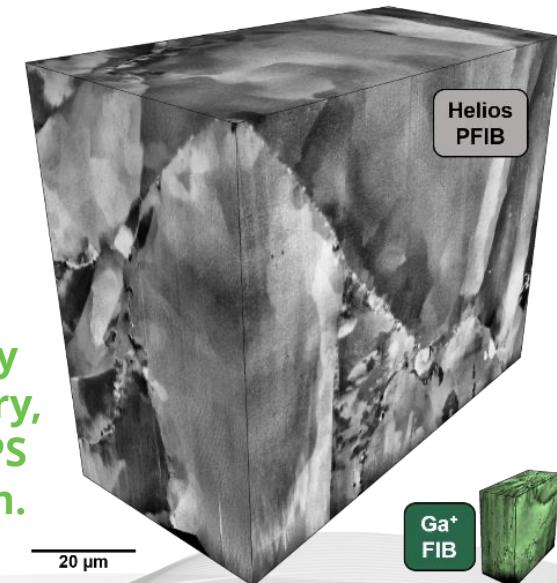


# PFIB - Benefits of the New *Plasma-FIB*



**Compared to traditional Ga<sup>+</sup> FIB**, PFIB can etch orders of magnitude larger sample areas, enabling large-scale 3D tomography.

With the addition of inert transfer & cryo capabilities, this new PFIB-SEM **will greatly advance BU's battery, biological, and CHIPS Act related research.**

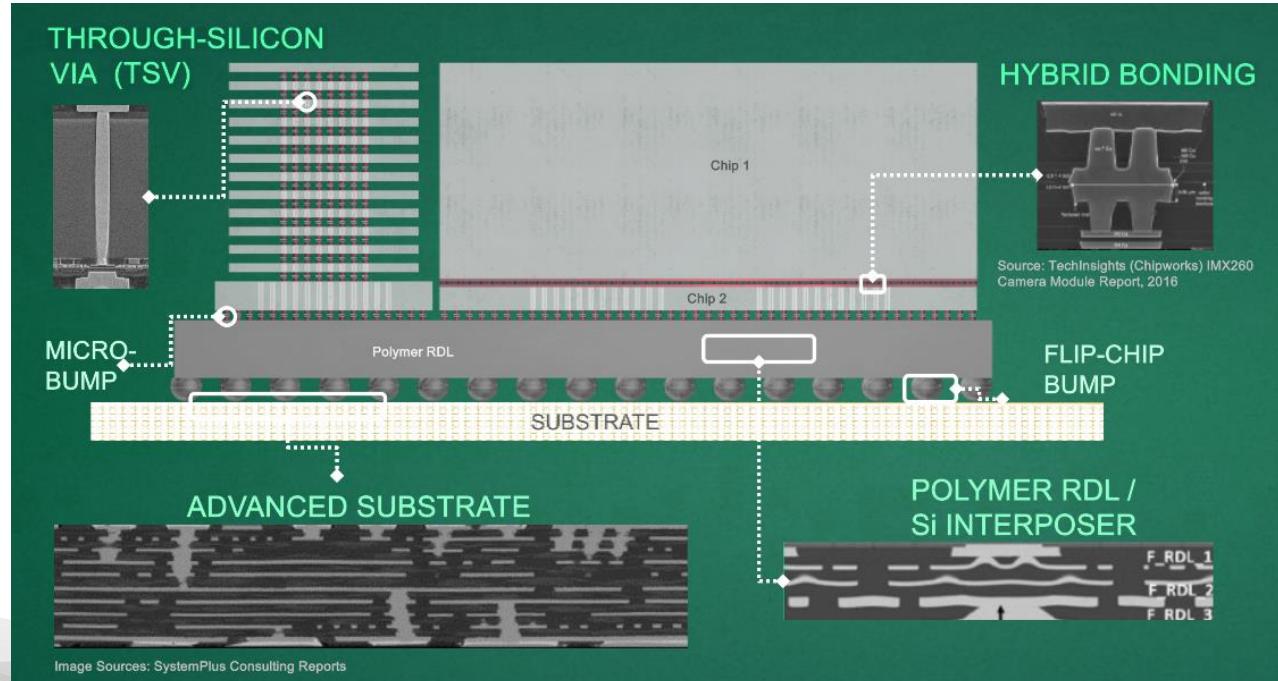


# PFIB - Fully Investigating 3D Packages

A more flexible FIB platform is needed to support hardware characterization and failure analysis on the **complex, next-gen, multi-scale, 3D packages** being developed.

**Investigating stacked chiplets requires both precise and large area milling of different types of materials.**

Helios 5 easily swaps between **high speed** (e.g., Xe) and **precise, smooth surface quality** sample milling (e.g., Ar).

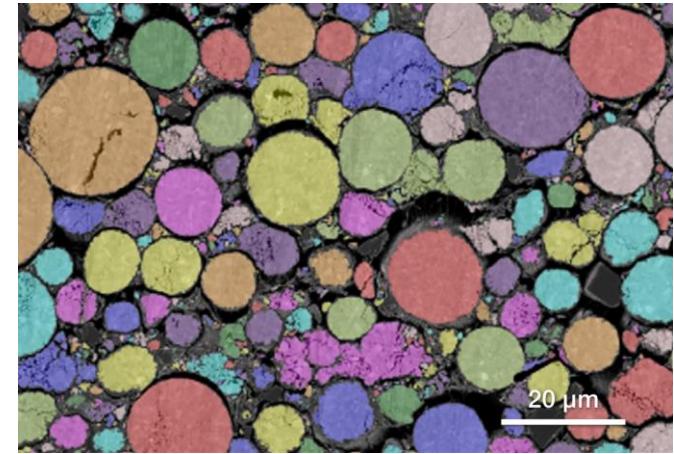


# PFIB - Analysis of Li-containing Materials

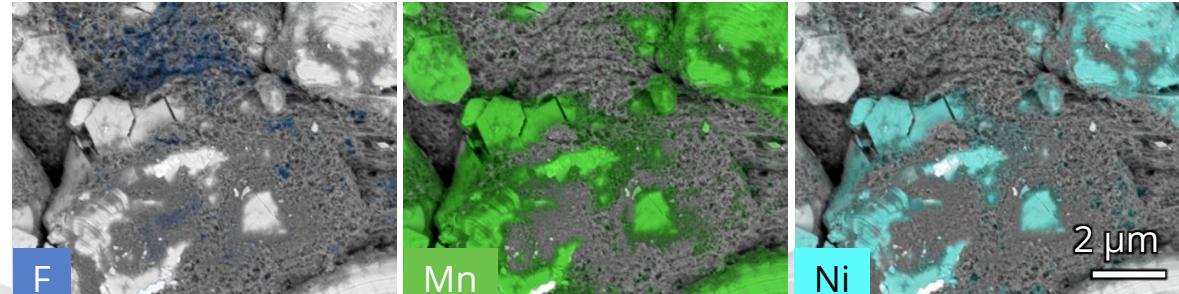
**PFIB with CleanConnect and cryo-stage** is ideal for investigating **Li-containing materials**.

CleanConnect allows samples to be introduced without air exposure, crucial for reactive samples like Li-ion battery cathode materials.

Cryo-stage reduces heat damage during milling **enabling study of unstable and/or delicate materials.**



Phase fraction analysis on NMC cathode cross-sectioned with PFIB.



Analysis of a Li-ion battery cathode composition using real-time EDS mapping.

# ADL Expansion: Surface Science Core Facility (SSCF)

3000 ft<sup>2</sup>, established 2022

**10** pieces of major instrumentation with future expansion plans

## Surface Analysis Suite

- **HAXPES-Lab**
  - Easy XAFS w/ Battery Cycler
  - FTIR Microscope
  - Raman Microscopes
  - SPM (AFM, STM, MFM, etc.)
  - Optical & Stylus Profilers
  - Laser Particle Size Analyzer

## Sample Prep Suite

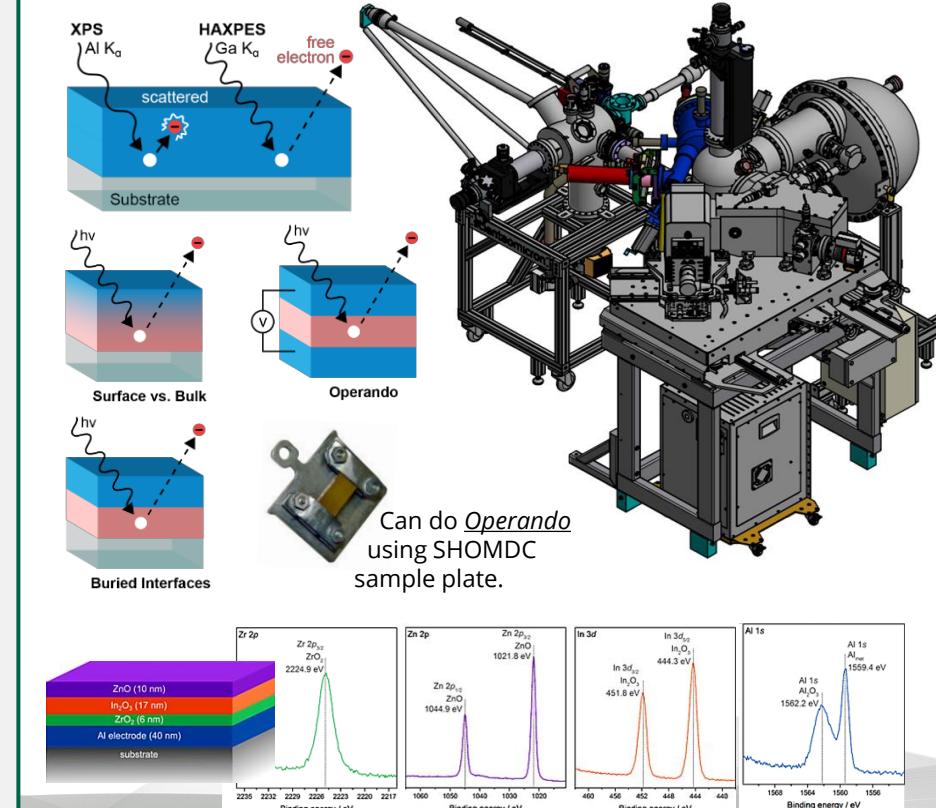
- Ar Glovebox
  - w/ UHV Transfer Suitcase



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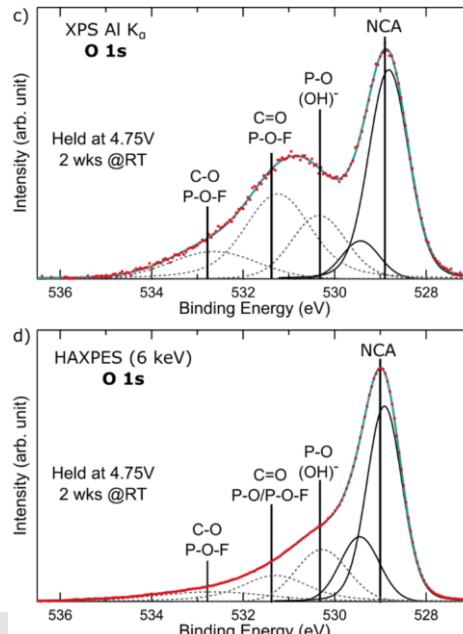
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## Equipment Spotlight: HAXPES-Lab Acquired using NSF MRI Grant

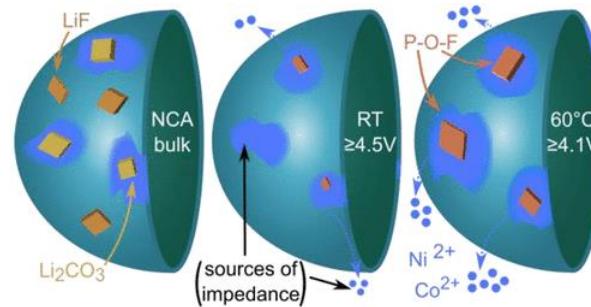


# HAXPES - Surface Compounds in Li-ion Cathodes

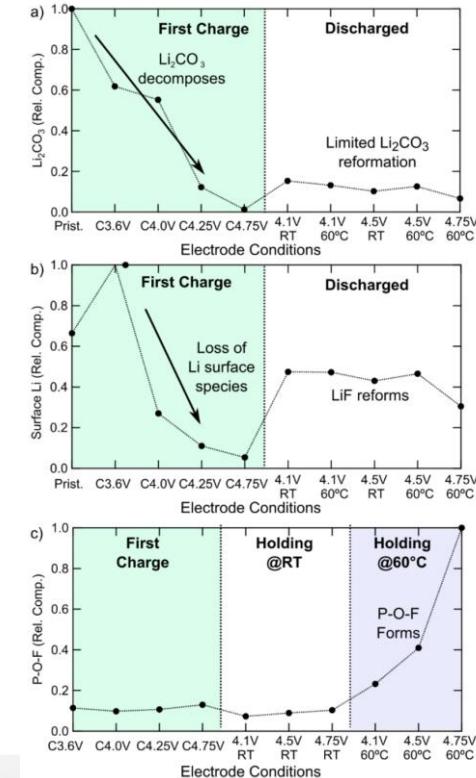
The combination of XPS and HAXPES enables comparison of surface vs bulk of battery cathodes & other materials.



Multiple photon energies provide information on the evolution of compounds formed at different depths during Li-ion battery cycling.



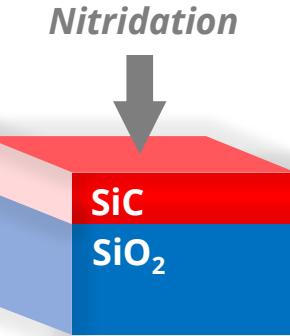
Lebens-Higgins, Z.W., et al. Evolution of the Electrode-Electrolyte Interface of  $\text{LiNi}_{0.8}\text{Co}_{0.15}\text{Al}_{0.05}\text{O}_2$  Electrodes Due to Electrochemical and Thermal Stress. *Chem Mater* **30**, 3, 958–969 (2018).



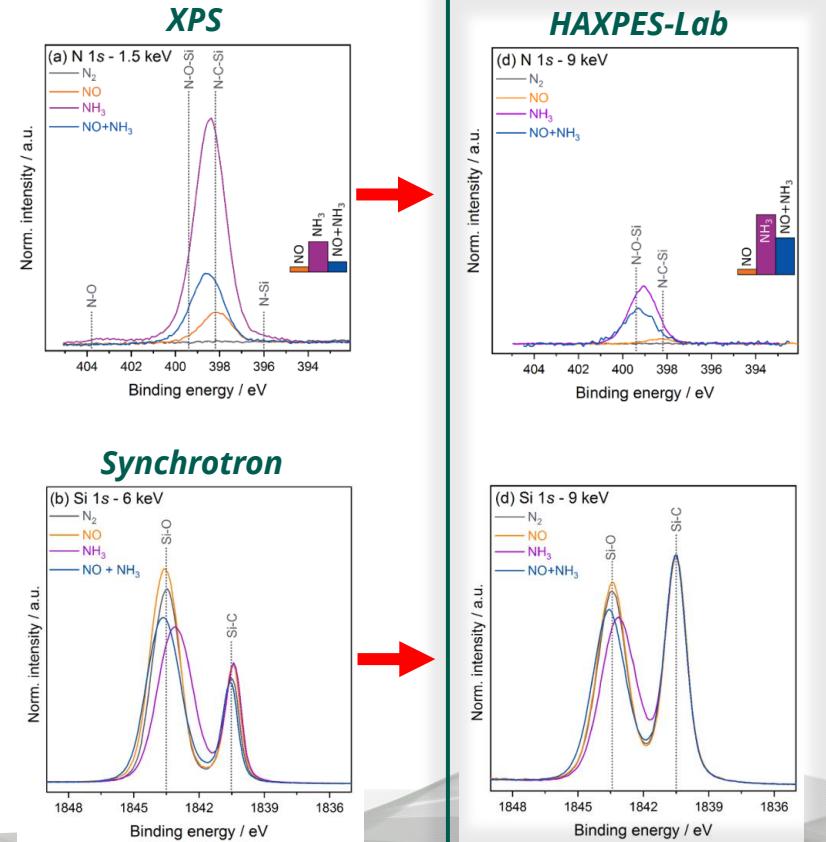
# HAXPES - Study of Interfacial Compounds

The combination of both XPS and HAXPES enables non-destructive depth studies on individual samples.

Using multiple X-ray energies, the effects of different nitridation processes on the SiC and  $\text{SiO}_2$  interface were tracked.



Berens, J. et al. Effects of nitridation on  $\text{SiC}/\text{SiO}_2$  structures studied by hard X-ray photoelectron spectroscopy. *J. Phys. Energy* 2, 035001 (2020).



\*6 keV HAXPES from synchrotron beamline (Diamond I09) with comparable capabilities.

# ADL Expansion: Nanofabrication Laboratory (NLAB)

1150 ft<sup>2</sup> class 1000 cleanroom space for  
4" wafer process, established 2015

## Photolithography Bay

- Mask/Contact Aligner
- Pattern Generator
- UV-Vis & 4-pt Probe

## Deposition & Wet Etching Bay

- RF Magnetron Sputter
- E-beam Evaporator
- ALD

## Metrology & Processing Bay

- RIE & Deep RIE
- RTP
- Profilometer & Microscope

**Equipment Spotlight:**  
Photolithography Bay  
*NLAB instrumentation upgrade*  
2024-2025



# About the IEEC

# IEEC Staff

Benson Chan  
S3IP Associate  
Director



S.B. Park  
IEEC Director



Steve Cain  
IEEC Lab Manager  
Interim Associate Director



The IEEC team offers over 120 years of industry experience to help students, faculty and industry members solve THEIR research problems.

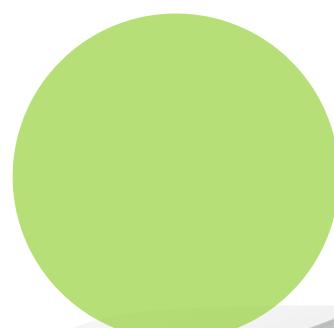
Son Tran  
Staff Scientist



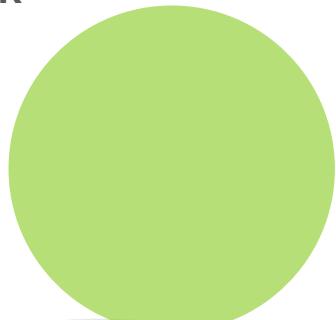
Bill Blazey  
Staff Scientist



Jim Wilcox  
Staff Scientist



Mike Gaynes  
Staff Scientist



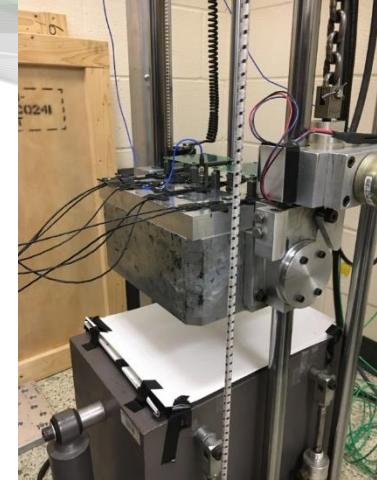
# IEEC Reliability Laboratory

## Environmental stress testing

- High temperature storage
- Low temperature storage
- Thermal cycling
- Air to air thermal shock
- Temperature and humidity
- Mechanical shock and vibration
- Electromigration evaluation

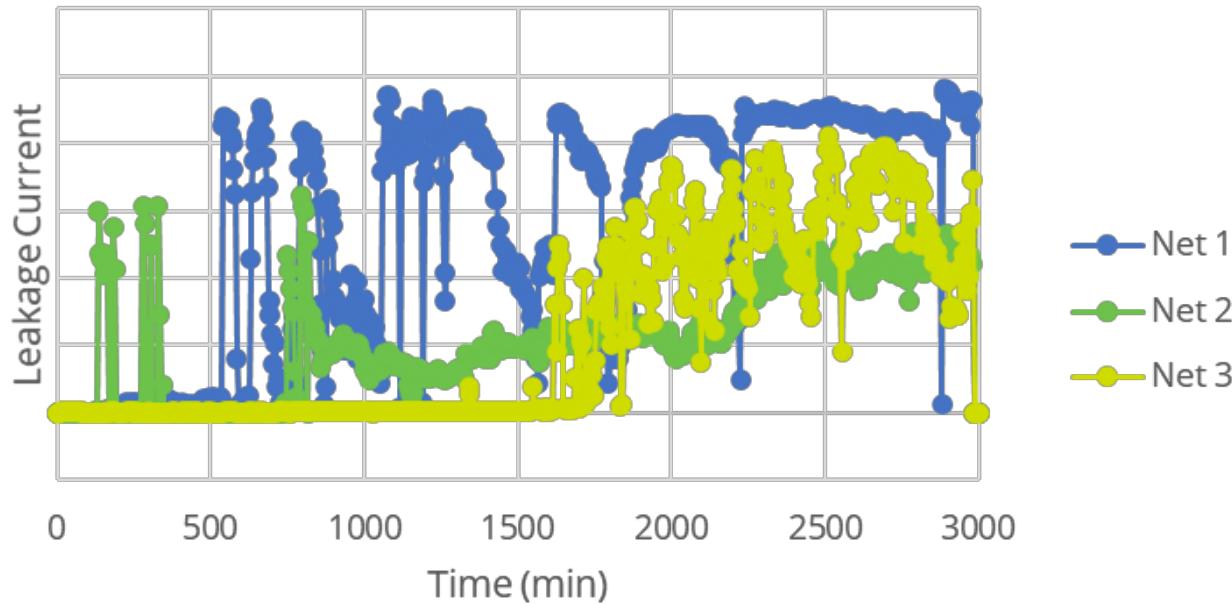
## Readout capabilities

- Interval and/or in situ readout
- DAQ each with up to 60 channels (individual), or 120 channels (common ground)
- Event detection, up to 8 channels

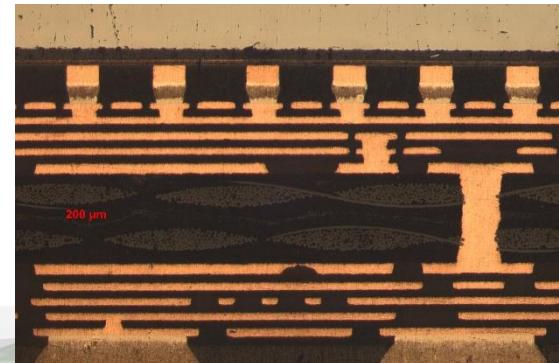
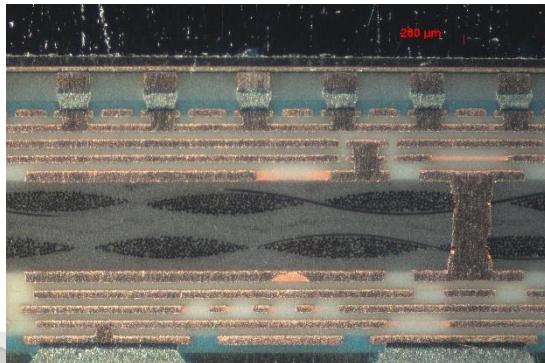
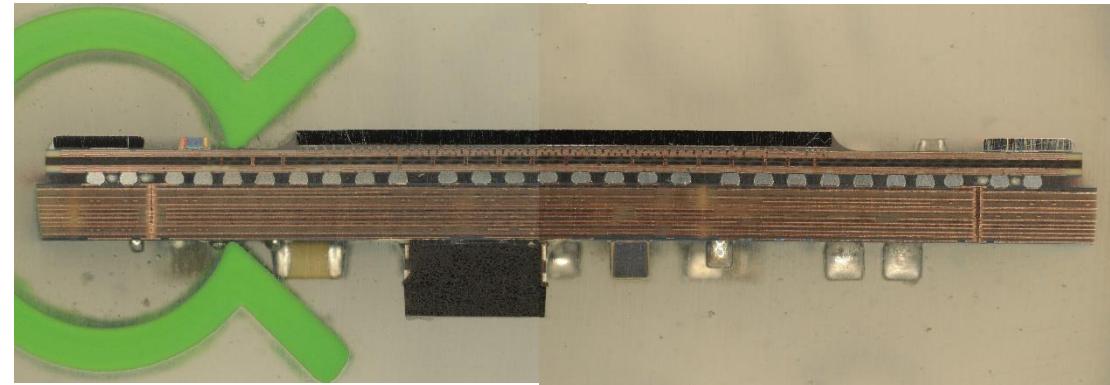


# Example – HAST Test on Glass Wafers

Leakage Current During 130C / 85% RH



# IEEC Cross Section & Optical Microscopy



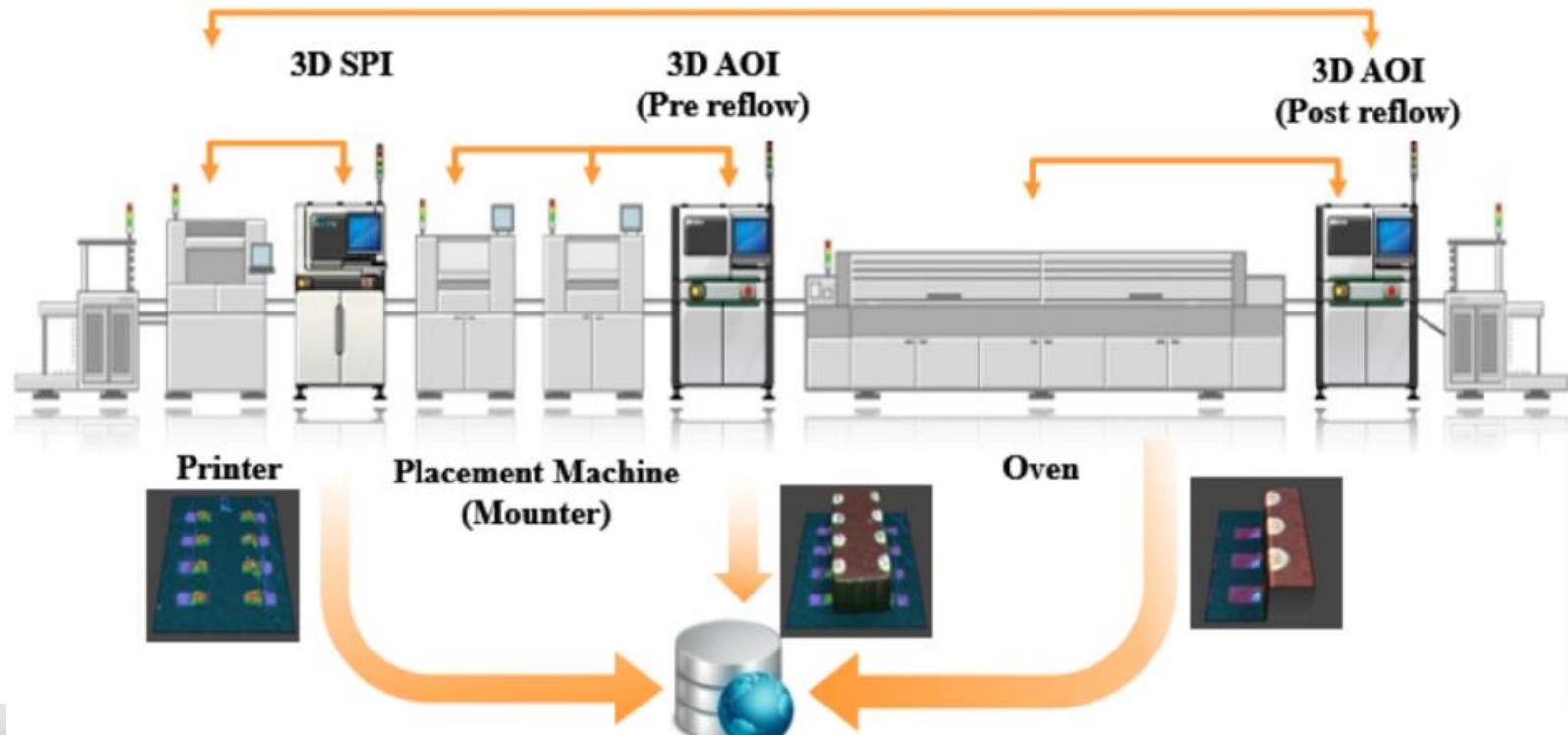
# Smart Electronics Manufacturing Laboratory

SEML is a prototype circuit board assembly laboratory

- Solder apply
- Component placement
- Automated inspection
- Reflow

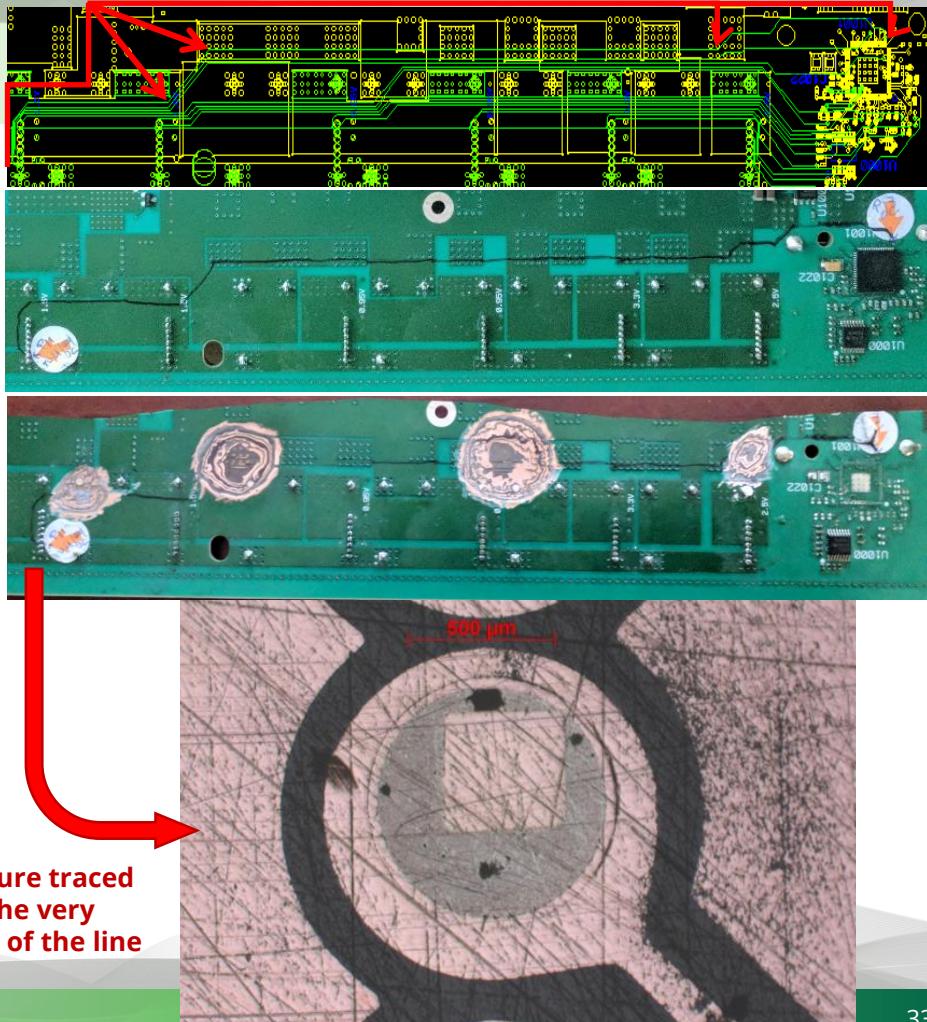


# SEML Research: System Learning and the Fully Automated Assembly Shop



# Failure Isolation and Analysis

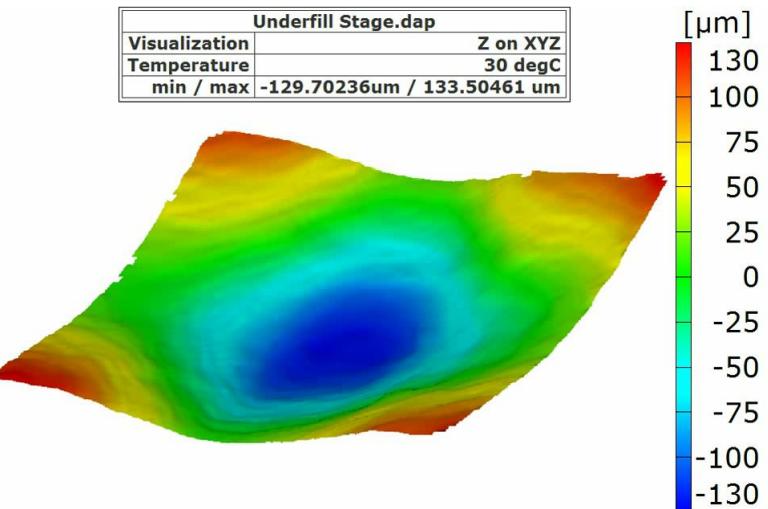
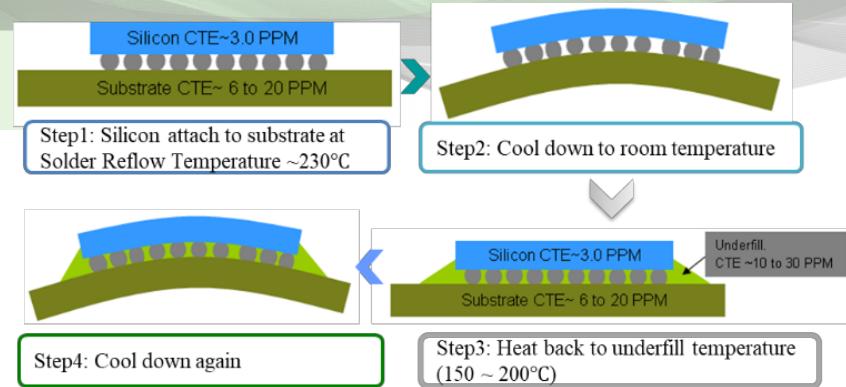
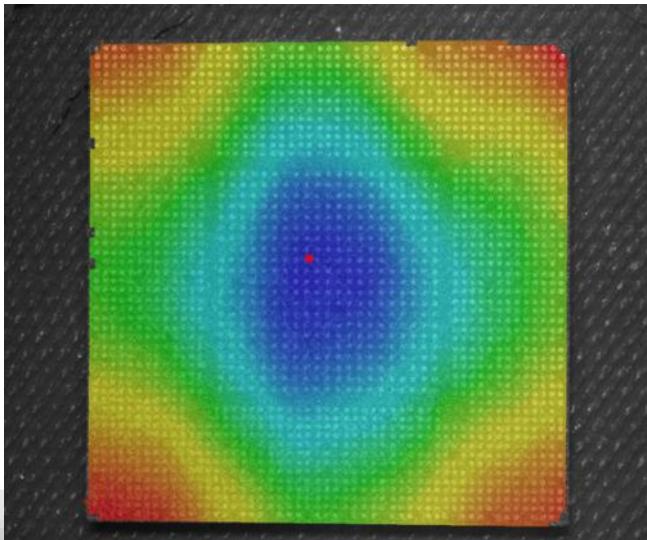
- Defective printed wiring board, 22 layers, circuit ran on layer 17
- Reviewed design data to determine trace routing
- Dig into board to determine intermediate routing points to isolate the defect
- Cause was drill smear preventing electrical connection from the Plated Through Hole and the copper trace



# 2.5D Warpage Studies

## Mismatch of thermal coefficient of expansion

- Non-uniform expansion / contraction of die and substrate
- Warpage of the package (major reliability concern)



# Industrial Pooled Research Projects

Project	Mentor Company
Soldering Below 150C – Superior Reliability?	Corning, BAE
Oxidation and Corrosion Induced Deterioration of Fatigue Resistance of Sintered Nano-Cu and Nano-Ag Bonds and Interconnects	Corning, AMD, BAE
SiC MOSFET Module Design for Ultra Low Inductance and Improved Thermal Conductivity for high Switching Frequency, High Voltage and High Current Applications	BAE, GE, ASE
$\mu$ +Net: Automating AdderNet Deployment and Acceleration on Microcontroller-based Platforms for Sustainable and Ubiquitous Edge AI	BAE, AMD
AI-Driven Inverse Design for Tailoring the Multidirectional Mechanical Properties of Stochastic Cellular Materials	AMD, Indium, Corning
Copper-based Nanoalloy Inks for Ambient- and High-Temperature Device Applications	BAE, GE
Smart Solutions for the Conformal Coating Progress: Optimizing Processes Parameters with AI-based Defects Detection	AMD, BAE
Simulating The Efficiency and Thermal Expansion of a Thermoelectric-Gated Transistor from First Principles	IBM
Modeling Current Flow through Interconnects with Thermal Atomic Motion and Alternating Bias	AMD

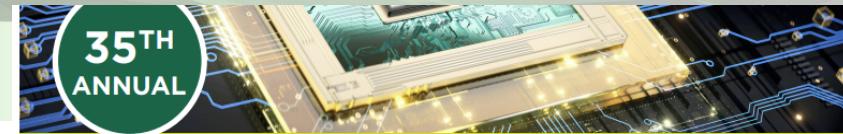
# Annual Electronics Packaging Symposium

- IEEC's flagship event: the premier packaging symposium in the Northeast
- 33 consecutive years\* with continued growth and returning participants
- 2024 Hosted by Binghamton University
  - Poster session with 26 entries
  - 2 keynote speakers
  - 25 talks by invited speakers
  - Panel session



The Small Scale Systems Integration  
and Packaging Center

A New York State Center of Excellence



**35TH ANNUAL**

## ELECTRONICS PACKAGING SYMPOSIUM

SEPTEMBER 4-5, 2024 • BINGHAMTON UNIVERSITY

Presented by: IEEC, Binghamton University •  
CAMM, Binghamton University • GE Aerospace • IBM Research

Binghamton University, GE Aerospace and IBM Research are proud to host the **35th Annual Electronics Packaging Symposium** — Small Systems Integration. The program will include two days of exciting invited presentations with a focus on supply chain interconnectivity. We invite you to join us for this event on Sept. 4-5, 2024, at Binghamton University's Innovative Technologies Complex. We look forward to seeing you in person.

The symposium brings together leaders in academia, industry and government to network and discuss the latest advances in the field of electronics packaging, and to bring value from the varying viewpoints of each respective sector.

The program will also include keynote presentations and student poster sessions. The goal of the symposium is to have those who attend walk away with insights, career-building opportunities and the knowledge of having been an integral part of the advancement of the electronics packaging field.

Session topics will include: future of computing for HPC/AI, flexible, additive and wearable electronics, heterogeneous integration, photonics packaging, thermal challenges, advanced substrates and power electronics.

A special panel on the expansion of electronics industry into India, chaired by Rao Tummala.

Event will include a special workshop on metrology hosted by NIST.

**Symposium agenda:**  
<https://www.binghamton.edu/ieec/eps/agenda.html>

Register: [bit.ly/3Vj1sPL](http://bit.ly/3Vj1sPL)

**TOPICS WILL INCLUDE:**

- Future of Computing for HPC/AI
- Flexible, Additive and Wearable Electronics
- Heterogeneous Integration
- Photonics Packaging
- Thermal Challenges
- Advanced Substrates
- Power Electronics

**For sponsor, exhibit and participant info, contact:**

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[www.binghamton.edu/ieec](http://www.binghamton.edu/ieec)



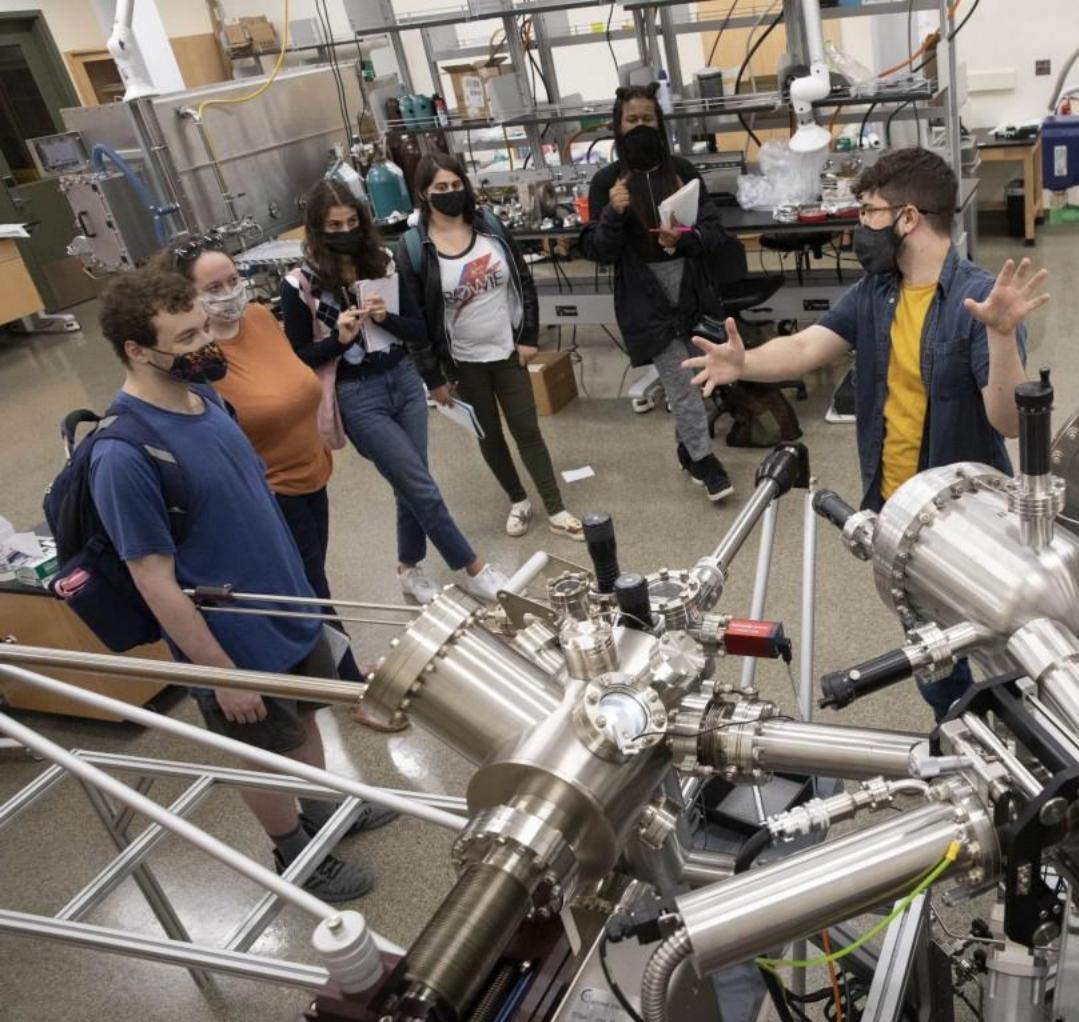
GE Aerospace



# ADL & IEEC Impact

With our current capabilities, we can serve the electronics packaging, material science, batteries, & health science research ecosystems.

*How can we  
collaborate?*



# THANK YOU

Dr. Jennifer Sammakia



ADL, S3IP, Binghamton University



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